
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: W. Thomas Novak

Attorney Docket No.:
NIKOP037/PA0502 00/04683

Application No.: To Be Assigned

Examiner: To Be Assigned

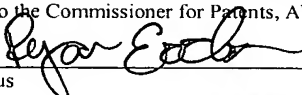
Filed: January 22, 2004

Group: To Be Assigned

Title: INTERFEROMETER SYSTEM FOR
MEASURING A HEIGHT OF WAFER STAGE

CERTIFICATE OF EXPRESS MAILING

I hereby certify that this paper and the documents and/or fees referred to as attached therein are being deposited with the United States Postal Service on January 22, 2004 in an envelope as "Express Mail Post Office to Addressee" service under 37 CFR §1.10, Mailing Label Number **EV334020373US**, addressed to the Commissioner for Patents, Alexandria, VA 22313-1450.


Ryan Eachus

**INFORMATION DISCLOSURE STATEMENT
37 CFR §§1.56 AND 1.97(b)**

Commissioner for Patents
Alexandria, VA 22313-1450

Dear Sir:

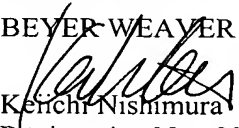
The references listed in the attached PTO Form 1449, copies of which are attached, may be material to examination of the above-identified patent application. Applicants submit these references in compliance with their duty of disclosure pursuant to 37 CFR §§1.56 and 1.97. The Examiner is requested to make these references of official record in this application.

This Information Disclosure Statement is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that these references indeed constitute prior art.

This Information Disclosure Statement is filed within three (3) months of the filing date of the above-referenced application. Accordingly, it is believed that no fees are due in connection with the filing of this Information Disclosure Statement. However, if it is determined that any fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 500388 (Order No. NIKOP037).

Respectfully submitted,

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Form 1449 (Modified) Information Disclosure Statement By Applicant (Use Several Sheets if Necessary)	Atty Docket No. NIKOP037/PA0502 00/04683	Application No.: To Be Assigned
	Applicant: W. Thomas Novak Filing Date January 22, 2004	Group To Be Assigned

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
	A	6,285,457	09/04/01	Ukaji			07/26/99
	B	6,208,407	03/27/01	Loopstra			07/13/98
	C	6,020,964	02/01/00	Loopstra, et al.			07/13/98
	D	5,917,580	06/29/99	Ebinuma, et al.			08/28/97
	E	5,416,562	05/16/95	Ota, et al.			06/22/94
	F	4,999,669	03/12/91	Sakamoto, et al.			07/12/89

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	G	EP 0 793 073 A2	03/09/97	EP			X	
	H	EP 0 077 878 A1	04/05/83	EP			X	
	I							
	J							
	K							

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	L	Patent Abstracts of Japan, Publication No. 61-196532, <i>Exposure Device</i> , Tsukamoto Izumi, filed 26/02/85.
	M	Patent Abstracts of Japan, Publication No. 57-183031, <i>Method For Wafer Exposure And Device Thereof</i> , Iwai Hiroshi, filed 06/05/81.
	N	
Examiner		Date Considered

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.